Silicon 3D detectors irradiated with pions and protons





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Results from irradiation: -Pions -Protons







## Introduction





## Fabrication steps





## Dry etching







Inductively Coupled Plasma

- Mask: photoresist
  Gas: SF<sub>6</sub>
  Coating: C<sub>4</sub>F<sub>8</sub>
- •**Diameter**: 10 µm
- •**Spacing**: 85 μm
- •**Depth**: 130 μm
- •Etch time: 100 minutes

#### Aspect ratio 13:1

#### Electrical contacts



#### •Metal evaporation:

Ti (50 nm) Au (105 nm)

#### •Tracks of Al (150 nm) (over the SiO<sub>2</sub> layer)

#### •Wire bonding (25 µm wire)



## Irradiation at PSI\*





\* Irradiation performed by K. Gabathuler, M. Glaser and M. Moll.

### Capacitance measurements (pions)



#### Leakage current (pions)





Fluence (1E12 pions/cm2)

#### Alpha spectroscopy



#### 5.5 MeV alpha in Si before irradiation



#### Alpha spectroscopy (irradiated)



5.5 MeV alpha in Si after 1E14 pi/cm2



#### Irradiation at CERN\*



# Irradiation with 24 GeV/c protons at CERN Flux of 1-3 x 10<sup>13</sup> p/cm<sup>2</sup>/h 7 fluences between 5 x 10<sup>12</sup> and 5 x 10<sup>14</sup> p/cm<sup>2</sup> 13 high resistivity n-type silicon samples

\* Irradiation performed by M. Glaser and M. Moll.

#### Leakage current (protons)



#### Capacitance measurements (protons)





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## In development



## Improved aspect ratio of vias -Dry etching (~30:1\*) -PhotoElectroChemical etching (>30:1\*)

Improved electrodes -pn junction

Improved readout electronics

 -MEDIPIX1\*
 -LHCb VELO
 -ATLAS SCT

\* 3D-RID collaboration: ppewww.ph.gla.ac.uk/3D-RID

## pn junction



#### Sample's preparation:

-creation of central via
-boron doping
-creation of surrounding vias
-metal evaporation



## 3D MEDIPIX1\*



#### **MEDIPIX** chip

- -Pixels per chip -64 x 64
- -Pixel size -170 x 170 μm<sup>2</sup>
- -Leakage current compensation
- -Sensitive to positive input charge only

Vias diameter: 10 μm Width of metal strips: 15 μm Pitch: 56.67 μm pc Cell pitch: 170.01 μm



\* 3D-RID collaboration: ppewww.ph.gla.ac.uk/3D-RID

## LHCb -VELO\*





\* Designed in collaboration with C. Parkes

## ATLAS SCT



Microstrips design (barrel)

-Small version (~1 cm<sup>2</sup>) -Channel: 128 + 2 •Strip: 20 μm x 1 cm 80 μm pitch

•Hexagonal cells

•Vias: 10 μm diameter 53.3 μm pitch



#### Conclusion





Results from irradiation: -Pions -Protons



In development: -pn junctions -proper readout electronics

## Reminder



